

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. ....09/360,292  
Filing Date ..... July 22, 1999  
Inventor..... Sujit Sharan et al.  
Assignee.....Micron Technology, Inc.  
Group Art Unit.....1765  
Examiner ..... Ahmed, Shamim  
Attorney's Docket No. ....MI22-1106  
Title: Plasma Etching Process

**RESPONSE TO NOVEMBER 30, 2006 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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**AMENDMENTS**

**Introductory Comments**

In response to the Office Action dated November 30, 2006, applicant amends and remarks as follows.